



IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 1765  
Examiner: To be assigned

In Re PATENT APPLICATION Of:

Applicant(s) : Toyo Kazu SAKATA

Serial No. : 10/721,260

Filed : November 26, 2003

For : Etching method and semiconductor device  
fabricating method

Attorney Ref: TAI 145

**STATUS REQUEST**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Please let us know the status of the above-identified application and when an  
Action may be expected. Please respond via facsimile or e-mail Tonya Harris (Docketing  
Manager) at [tonya@rabinchamp.com](mailto:tonya@rabinchamp.com).

Respectfully submitted,

*Steven M. Rabin*

June 2, 2005  
Date

SMR:klc

Steven M. Rabin  
Registration No. 29,102  
**Customer No. 23,995**  
Tel: (202) 371-8976  
Fax: (202) 408-0924